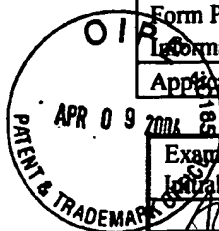


Form PTO-1449 (modified by applicant)	Dock. #: 1FALL112903	Applic #: 10/724535
Information disclosure citation in an application	Filing Date: 12/29/03	Group art unit: 3723
Applicants: Charles J. Molnar/		



US Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
AD	6298470	8-2-2001	Breiner et al.	716	4	
	6293851	9-25-01	Molnar	451	41	
	6291349	9-18-01	Molnar	438	609	
	6283829	9-4-01	Molnar	451	8	
	6268641	7-31-01	Yano et al.	257	260	
	6267644	7-31-01	Molnar	451	41	
	6263255	7-17-01	Tan et al.	700	121	
	6257953 b1	7-10-01	Gittis et al.	451	5	
	6197604 B1	3-6-01	Miller	438	14	
	6121143	9-19-00	Messner et al.	438	692	
	5993298	11-30-99	Duescher	451	56	
	5985045	11-16-99	Kobayashi	148	240	
	5972793	10-26-99	Tseng	438	692	
	5968280	10-19-99	Ronay	134	2	
	5958794	9-28-99	Bruxvoort	438	692	
	5954997	9-21-99	Kaufman	252	79.1	
	5954975	9-21-99	Cadien	216	38	
	5945347	8-31-99	Wright	438	692	
	5934978	8-31-99	Burke	451	A36	
	5919082	7-6-99	Walker	451	41	
	5916855	6-29-99	Avanzino	51	307	
	5910041	6-8-99	Duescher	451	28	
	5906754	5-25-99	Appel	216	88	
	5885334	3-23-99	Suzuki	438	639	
AD	5885137	3-23-99	Ploessl	106	3	

Foreign Patent Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
AD	WO 99/64527	12-16-99	Sachan et al.	C09G	1/02	
	WO 98/08919	3-5-98	Kalota et al.	C10M	A2	
	WO 00/00567	1-6-00	Kaufman et al.	C09K	3/14	
AD	WO 00/00561	1-6-00	Kaufman et al.	C09G	1/02	

Other documents (including Author, Title, Date, Pertinent pages, etc.)

AD	6204181 withdrawn from issue, Molnar, filed 11-5-99, published March 20, 2001, serial number 09/438180
AD	BERMAN, MIKE et al., "Review of in Situ and in Line Detection for CMP Applic.", Semiconductor Fabtech, 8 th edition, pp. 267-274.
AD	BIBBY, THOMAS, "Endpoint Detection for CMP", Journal of Electronic Materials, Vol. 27, #10, 1998, pp. 1073-1081.

Examiner: Anthony Ojini	Date considered: 6-10-05
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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	5876490	3-2-99	Ronay	106	3	
	5876266	3-1-99	Miller	451	56	
	5860847	1-19-99	Sakurai et al.	451	10	
	5858813	1-12-99	Scherber	438	693	
	5842909	12-1-98	Sandhu	451	7	
	5833519	11-10-98	Moore	451	56	
	5830280	11-3-98	Sato	134	2	
	5783489	7-21-98	Kaufman	438	692	
	5762537	6-9-98	Sandhu	451	7	
	5759917	6-2-98	Grover et al.	438	690	
	5749769	5-12-98	Church	451	5	
	5743784	4-28-98	Birang	451	21	
	5740033	4-14-98	Wassick et al.	364	149	
	5738562	4-14-98	Doan	451	5	
	5735036	4-7-98	Barr	29	603.12	
	5733819	3-31-98	Kodama	438	692	
	5733176	3-31-98	Robinson	451	41	
	5728308	3-17-98	Muroyama	216	88	
	5722879	3-3-98	Cronin	451	281	
	5695660	12-9-97	Litvak	216	85	
	5695384	12-9-97	Beratan	451	28	
	5691895	11-25-97	Kurtzberg et al.	364	148	
	5685766	11-11-97	Mattingly	451	36	
	5667629	9-16-97	Pan	438	13	
	5647952	7-15-97	Chen	156	636.1	
	5643060	7-1-97	Sandhu	451	285	
	5639388	6-17-97	Kimura	216	84	
	5614444	3-25-97	Farkas	437	225	
	5609517	3-11-97	Lofaro	451	529	
	5609511	3-11-97	Moriyama	451	5	
	5597442	1-28-97	Chen	156	626.1	
	5595526	1-21-97	Yau	451	8	
	5537325	7-16-96	Iwakiri et al.	364	468.28	
	5413941	5-9-95	Koos	437	8	

Foreign Patent Documents

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Other documents (including Author, Title, Date, Pertinent pages, etc.)

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Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
<input checked="" type="checkbox"/>	5352277	10-24-94	Sasaki	106	6	
<input checked="" type="checkbox"/>	5340370	8-23-94	Cadien	51	38	
<input checked="" type="checkbox"/>	5314843	5-24-94	Yu	437	225	
<input checked="" type="checkbox"/>	5308438	5-3-94	Cote	156	636	
<input checked="" type="checkbox"/>	5196353	3-23-93	Sandhu	437	7	
<input checked="" type="checkbox"/>	5166080	11-24-92	Schietinger	437	7	
<input checked="" type="checkbox"/>	5154512	10-13-92	Schietinger	374	9	
<input checked="" type="checkbox"/>	5137544	8-11-92	Medillin	51	308	
<input checked="" type="checkbox"/>	5107445	4-21-92	Jensen	36	525	
<input checked="" type="checkbox"/>	5069002	12-3-91	Sandhu	51	165R	
<input checked="" type="checkbox"/>	4421068	12-20-83	Aral	122	448	

Foreign Patent Documents

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Other documents (including Author, Title, Date, Pertinent pages, etc.)

<input checked="" type="checkbox"/>	"Understanding and Using Cost of Ownership", Wright Williams & Kelly, Dublin, CA, rev 0595-1
<input checked="" type="checkbox"/>	"Intermetal Dielectric Cost-of-Ownership", Case, C.B. and Case, C. J., <u>Semiconductor International</u> , June 1995, pp 83-88
<input checked="" type="checkbox"/>	"Using COO to select Nitride PECVD clean cycle", Anderson, Bob, et al., <u>Semiconductor International</u> , Oct. 1993, pp 86-88
<input checked="" type="checkbox"/>	"The application of cost of ownership simulation to wafer sort and final test", Jimez, D: W. et al., SEMI's Manufacturing test Conference, July, 1993
<input checked="" type="checkbox"/>	"Reducing Tungsten Deposition equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , Oct. 1992, pp 23-25
<input checked="" type="checkbox"/>	"Reducing ion-implant equipment cost of ownship through in situ contamination prevention and control", Burghard, R. W., et al., <u>Microcontamination</u> , Sept. 1992, pp 27-30
<input checked="" type="checkbox"/>	"Reducing tungsten-etch equipment cost of ownership through in sity contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , June 1992, pp 33-36
<input checked="" type="checkbox"/>	"Reducing process equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , May. 1992, pp 21-24
<input checked="" type="checkbox"/>	"Cost of ownership for inspection equipment", Dance D. and Bryson, P., Sematech, Austin, Texas, date unknown

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